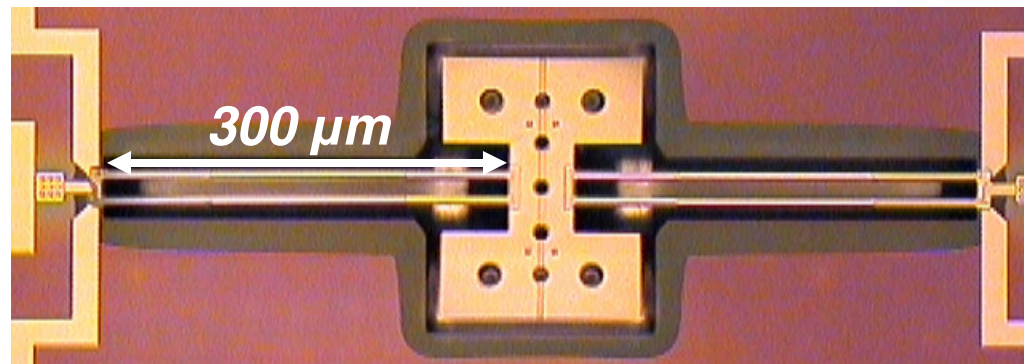




POST-CMOS COMPATIBLE AIN RESONANT ACCELEROMETERS

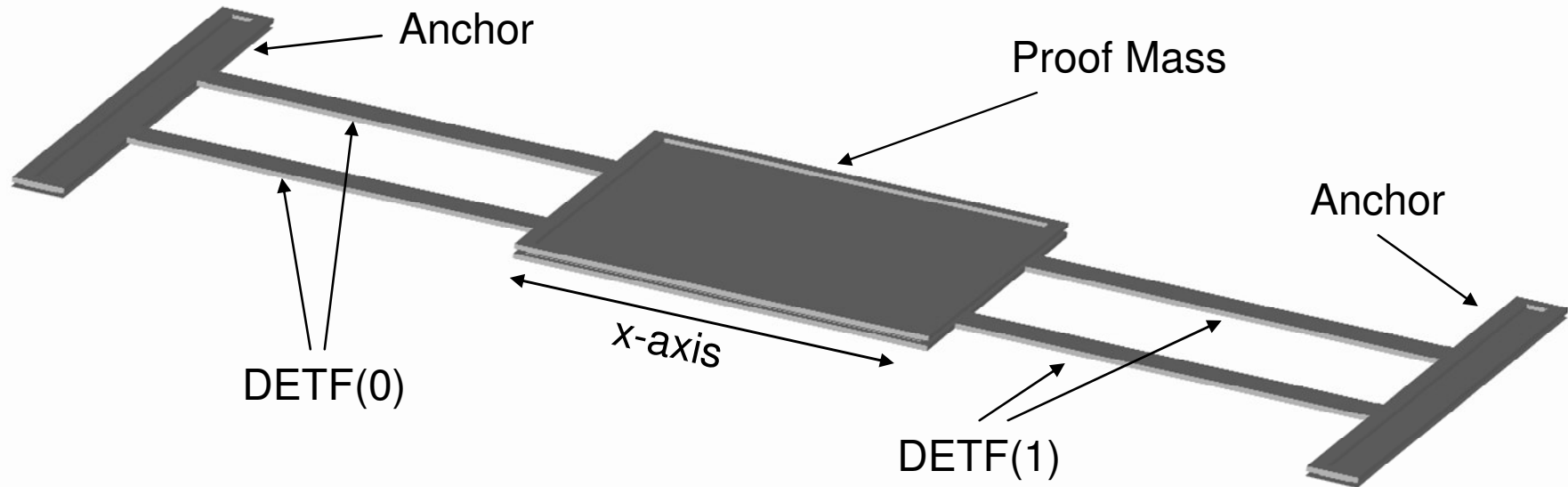
- **Goal:** To develop small, low power accelerometers that can be placed directly on-top of foundry CMOS circuitry.
 - Resolution $< 10 \text{ mG}/\sqrt{\text{Hz}}$
 - Bandwidth 10 Hz – 1 kHz
 - CMOS compatible materials, max. processing temp = 400 °C
- **Approach:**
 - Develop post-CMOS compatible, piezoelectric thin film MEMS process
 - Design and fabricate accelerometers
 - Design readout circuitry and measure acceleration resolution

Team: Roy Olsson (PI),
Ken Wojciechowski,
Mike Baker, Ken Pohl,
Steve Yepez, Jim
Stevens, Melanie
Tuck, and Jim Fleming





Resonant Accelerometer Operation and Properties



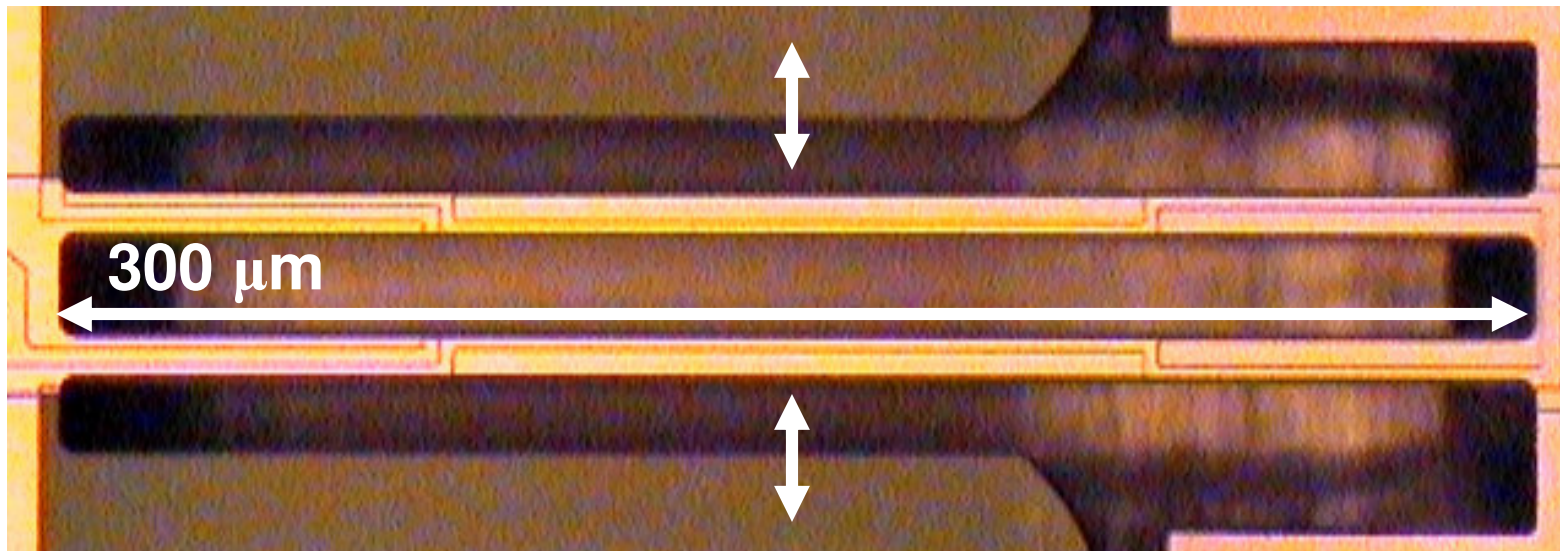
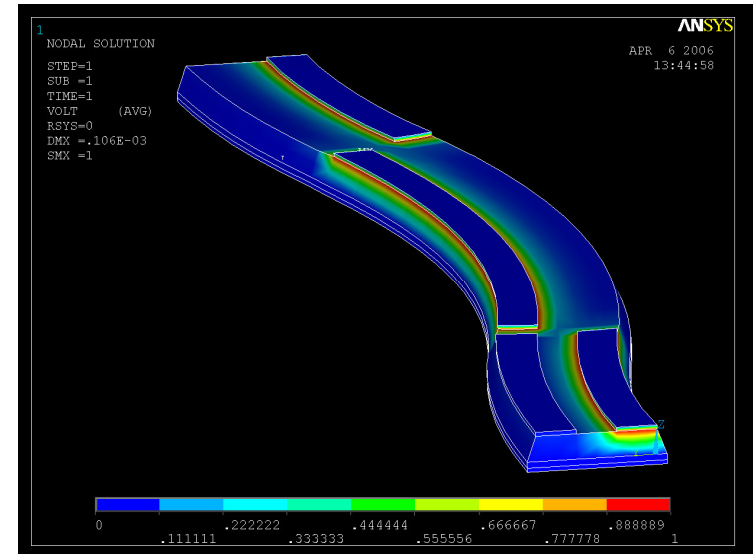
- Double-ended tuning forks (DETF) placed in oscillation loop
- Positive x acceleration increases frequency of DETF(0), decreases frequency of DETF(1)
- Differential design improves cross-axis rejection, reduces temperature sensitivity, high dynamic range
- Low power digital output
- Measures strain not displacement, high stiffness, lower masses, more reliable and easier to fabricate



DETF Sensing Beams

- **Double-Ended Tuning Fork (DETF)**

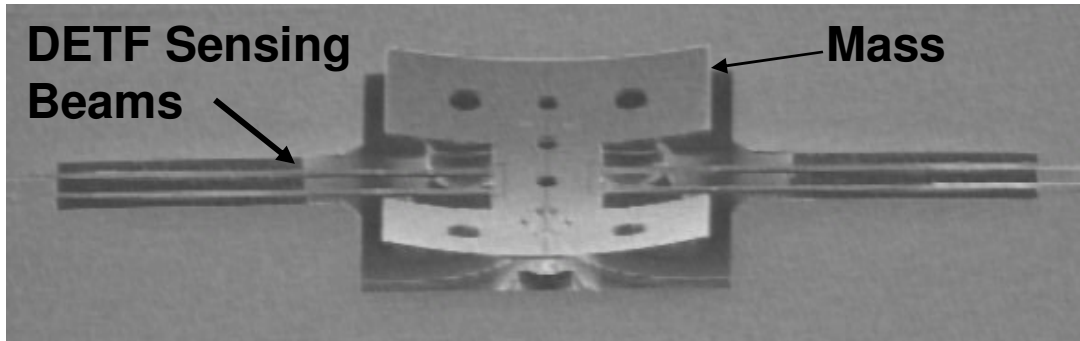
- Electric field across AlN film causes lateral displacement due to d_{31} piezoelectric coefficient
- DETF mode driven through electrode layout
- DETF mode reduces anchor losses



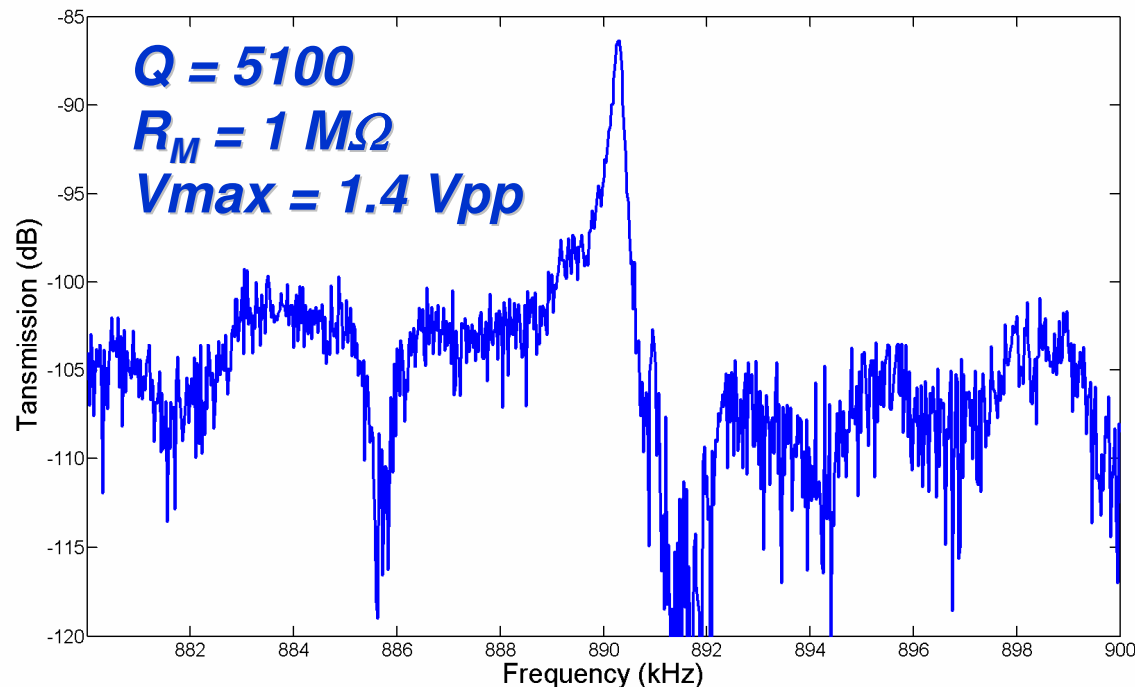
890 kHz Double-ended tuning fork resonant sensing beams



Aluminum Nitride Piezoelectric Transduction



AIN Resonant Accelerometer



Frequency Response of DETF Sensing Beams

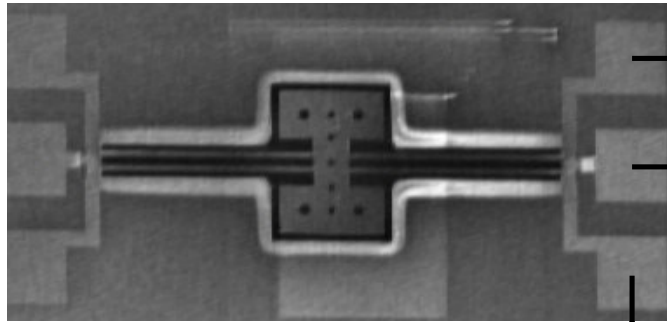
Piezoelectric Transduction

- Low Impedance
- Linear with Drive Voltage (10x Higher Power Handling)
- 1.4x Lower Q than Electrostatic Si Beam Sensors (Offset by Improved Power Handling)
- Post CMOS Compatible Materials

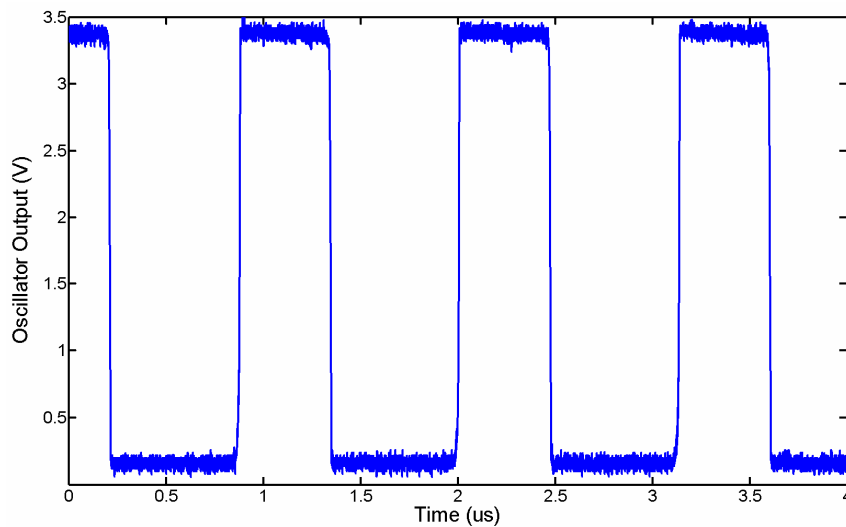
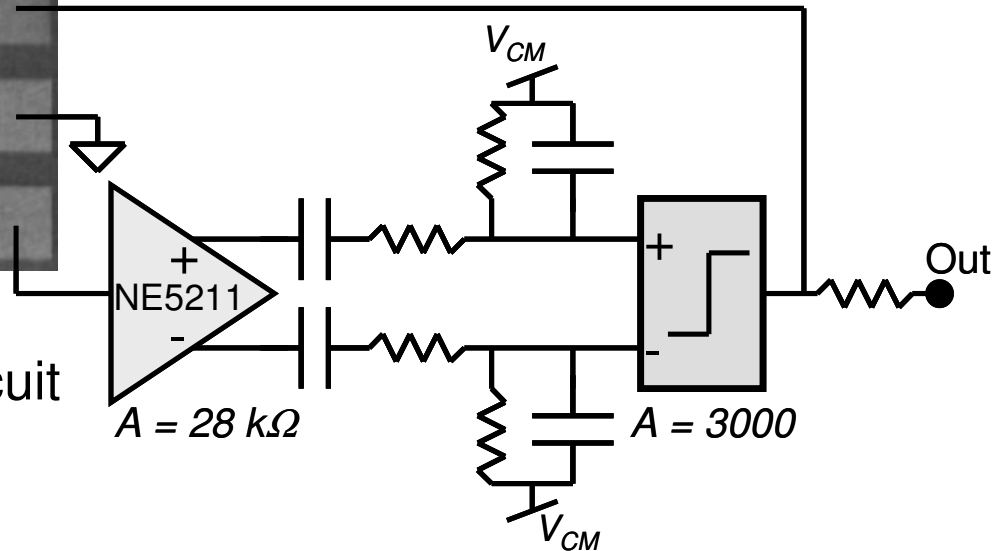
High-Q enables very accurate frequency and thus acceleration measurement



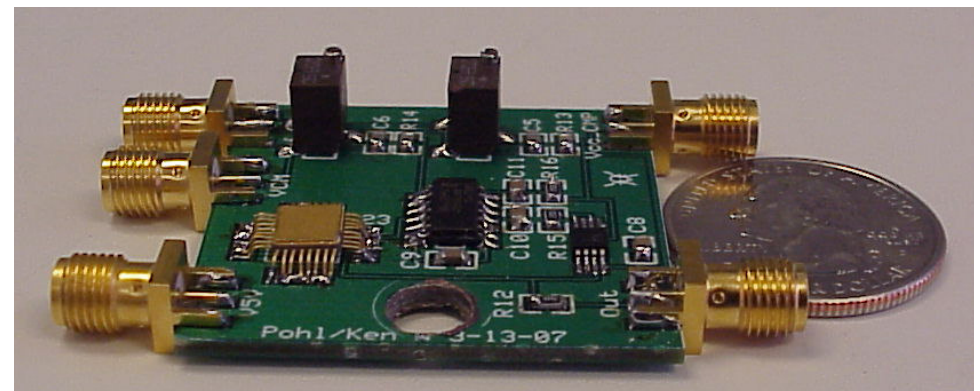
DETF Oscillator Readout Circuit



DETF Oscillator Readout Circuit



Output of the DETF Oscillator



Packaged Accelerometer and PCB Readout Electronics



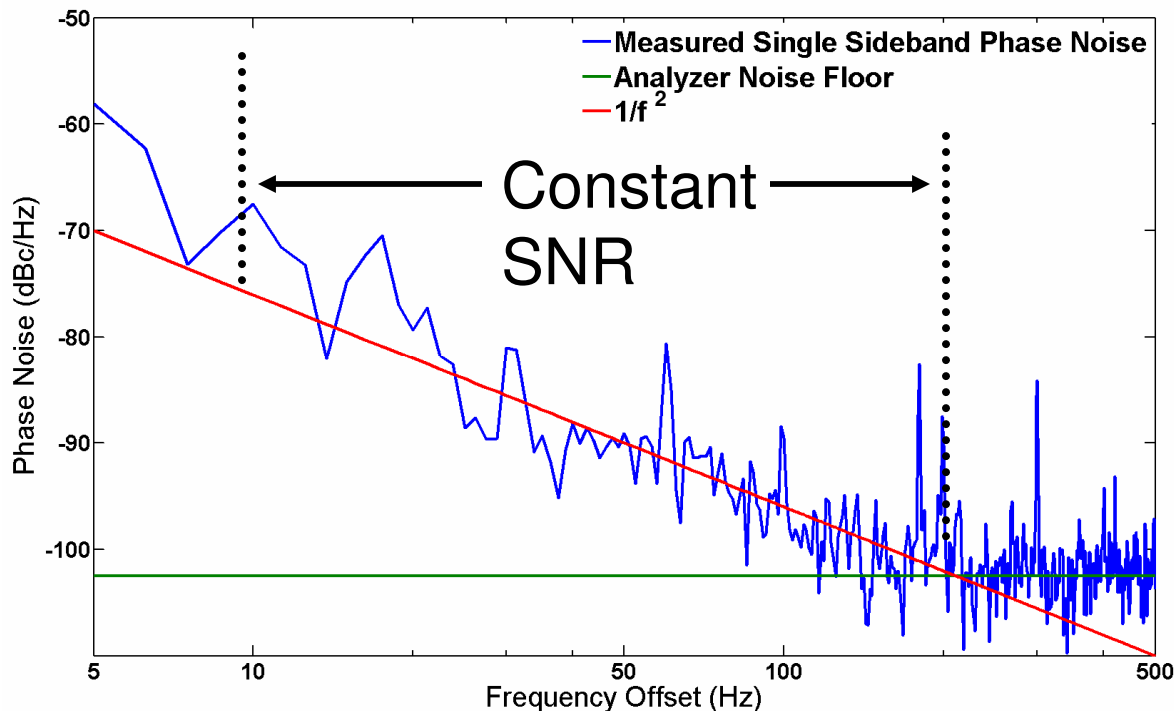
Accelerometer Performance Analysis

Readout Oscillator Circuit Phase Noise

$$L_{osc}(\Delta f) = 10 \log \left[\frac{2KT}{P_{sig}} \left(\frac{f_0}{2Q\Delta f} \right)^2 \right]$$

Vibration Induced Signal

$$L_v(\Delta f_v) = \left(\frac{|\vec{\Gamma}| f_0 \vec{a}(f_v)}{2f_v} \right)^2$$

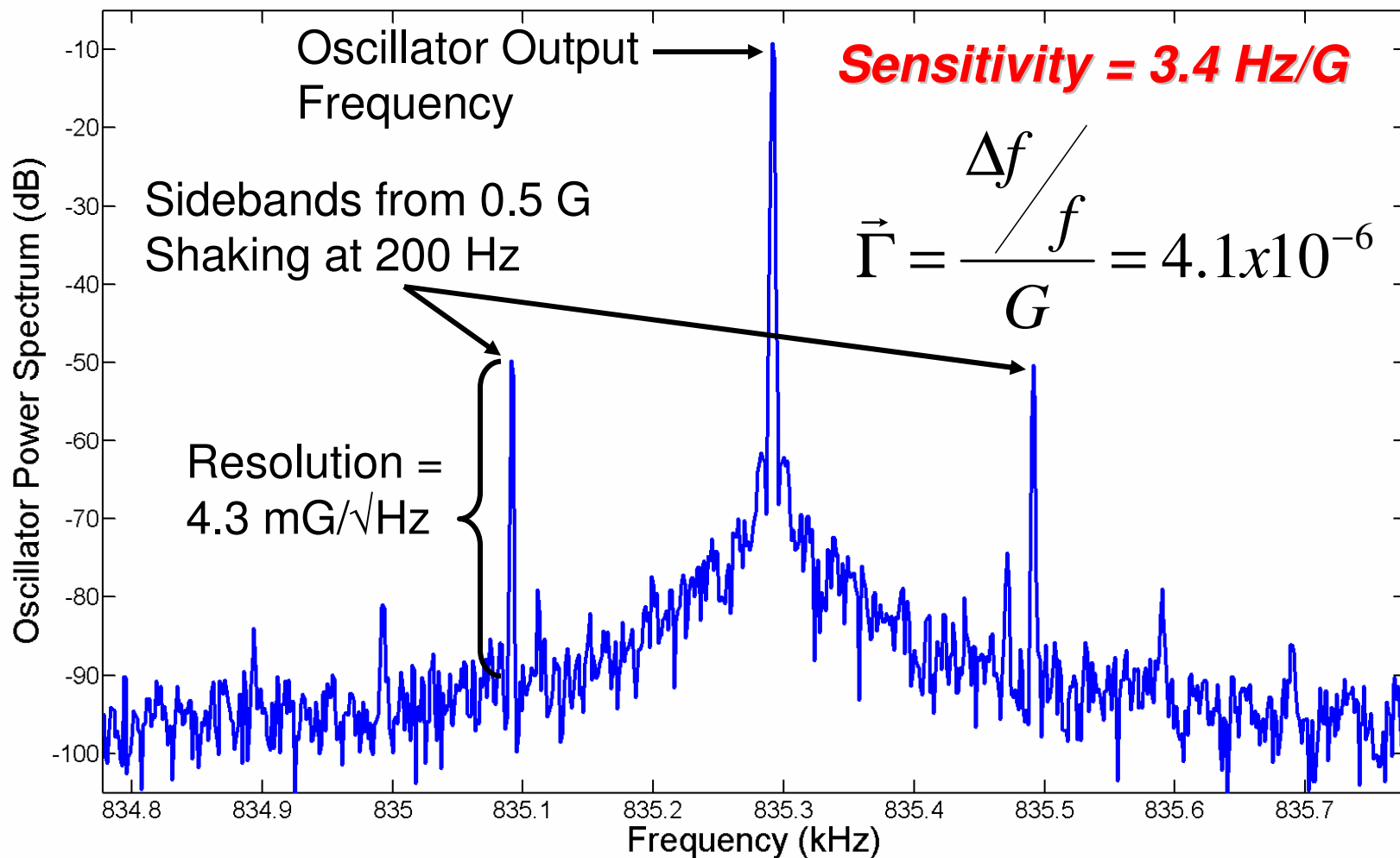


Accelerometer Resolution

$$\frac{a_{\min}(f_v)}{\sqrt{Hz}} = \frac{2f_v \sqrt{L_{osc}(\Delta f_v)}}{\vec{\Gamma} f_0}$$



Acceleration Measurement

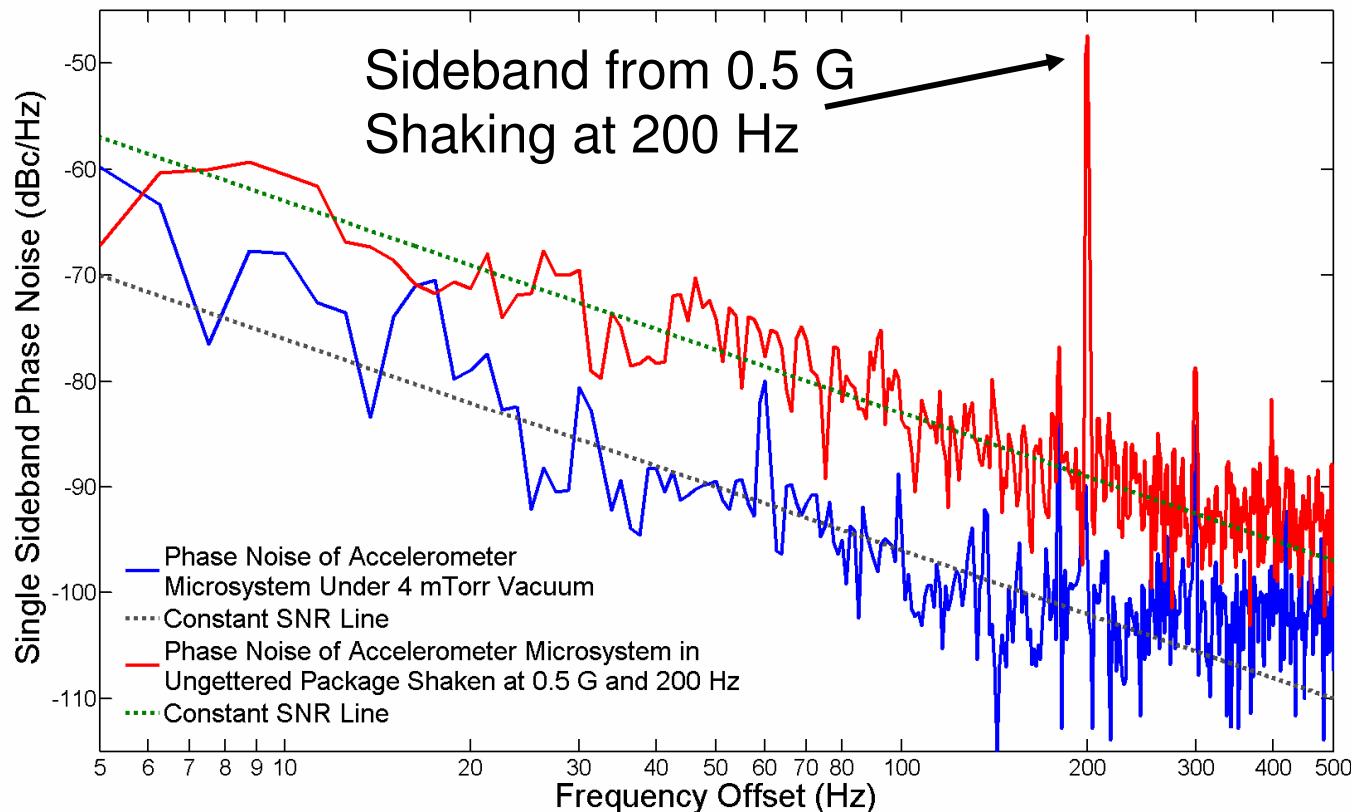


Shaker Testing on an AlN Resonant Accelerometer in a Chip Scale Vacuum Package Without Getters



Accelerometer Performance

<i>Vacuum</i>	<i>Mass Width</i>	<i>Mass Length</i>	<i>Thickness</i>	<i>Mass</i>	<i>Resolution</i>
<i>Ungettered</i>	<i>200 μm</i>	<i>150 μm</i>	<i>1.35 μm</i>	<i>120 ng</i>	<i>4 mG/$\sqrt{\text{Hz}}$</i>
<i>4 mTorr</i>	<i>200 μm</i>	<i>150 μm</i>	<i>1.35 μm</i>	<i>120 ng</i>	<i>0.9 mG/$\sqrt{\text{Hz}}$</i>
<i>4 mTorr</i>	<i>2 mm</i>	<i>2 mm</i>	<i>1.35 μm</i>	<i>15.6 μg</i>	<i>7 $\mu\text{G}/\sqrt{\text{Hz}}$</i>



Significance

- Very high resolution for a given proof mass (30x > than capacitive sensing)
- Inertial sensors integrated over custom CMOS signal processing and RF communications circuitry